ABSTRACT

Method for transferring InP film

A method for transferring InP film onto a stiffener substrate, the method comprising the steps consisting of:

a) Providing a structure comprising an InP surface layer (5) and an underlying doped thin InP layer (4);

b) Implanting hydrogen ions through the surface layer (5) so as to create a weakened plane (7) in the doped thin layer (4), delimiting a film comprising the surface layer (5);

c) Placing the surface layer (5) in close contact with a stiffener substrate; and

d) Applying heat treatment to obtain splitting at the weakened plane (7) and transfer of the film onto the stiffener substrate.

Figure 4